

Atty. Docket No. OF03P106/US

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF: :

Tae Woo KIM : GROUP ART UNIT:

SERIAL NO: NEW APPLICATION :

FILED: JULY 25, 2003 : EXAMINER:

FOR: METHOD FOR FABRICATING
MOS TRANSISTORS

I hereby certify that this document is being deposited with the United States Postal Service as first class mail in an envelope addressed to Commissioner for Patents, Washington, D.C. 20231, on July 25, 2003.

By:

Andrew D. Fortney

REQUEST FOR PRIORITY UNDER 35 U.S.C. 119(a)-(b) AND 37 C.F.R. 1.55

COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

Applicant respectfully requests the benefit of the filing date of the following prior foreign application(s) under the Paris Convention for the Protection of Intellectual Property:

<u>Serial No.</u>	<u>Filing Date</u>	<u>Country of Filing</u>
10-2002-0043794	July 25, 2002	Republic of Korea

A certified copy of the priority application will be filed before any U.S. patent issues from the above-captioned application.

Respectfully submitted,

AdS

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